



IFW

**IN THE UNITED STATES PATENT AND TRADEMARK OFFICE**

In re Patent Application of

HATADA et al

Atty. Ref.: LSN-2635-197

Serial No. 10/743,409

TC/A.U.: 1753

Filed: December 23, 2003

Examiner:

For: GAS CONCENTRATION MEASURING APPARATUS

\* \* \* \* \*

January 22, 2007

Commissioner for Patents

P.O. Box 1450

Alexandria, VA 22313-1450

Sir:

**INFORMATION DISCLOSURE STATEMENT**

Attention is directed to the attached Japanese Office Action (and English translation) in a counterpart of this application and to a copy of each non-US patent document newly cited therein. A Form PTO/SB/08a is also attached.

Official consideration and citation of all identified documents is requested.

Respectfully submitted,

**NIXON & VANDERHYE P.C.**

By:

Larry S. Nixon  
Reg. No. 25,640

LSN:vc

901 North Glebe Road, 11th Floor

Arlington, VA 22203-1808

Telephone: (703) 816-4000

Facsimile: (703) 816-4100

